



PATENT

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Case Docket No. RYUKA.002AUS

Date: September 30, 2005

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Kouji Fujiyoshi et al.

App. No. : 10/712,594

Filed : November 12, 2003

For : ELECTRON BEAM EXPOSURE APPARATUS,
ELECTRON BEAM EXPOSING METHOD, SEMICONDUCTOR
ELEMENT MANUFACTURING METHOD, AND PATTERN
ERROR DETECTION METHOD

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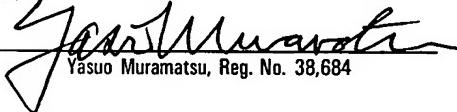
Examiner : William D. Coleman

Art Unit : 2823

I hereby certify that this correspondence and all marked attachments
are being deposited with the United States Postal Service as first
class mail in an envelope addressed to: Commissioner for Patents,
P.O. Box 1450, Alexandria, VA 22313-1450, on

September 30, 2005

(Date)


Yasuo Muramatsu, Reg. No. 38,684

TRANSMITTAL LETTER

COMMISSIONER FOR PATENTS
ALEXANDRIA, VA 22313-1450

Dear Sir:

Transmitted herewith is a response to office action in the above-identified utility application.

An extension of time to respond for * month(s) is hereby requested.

Time Extension Fee:

- one month (\$120 large entity)
 two months (\$450 large entity)
 three months (\$1020 large entity)

Enclosed are:

- Amendment in 28 pages.
 Certified copies of JP 2001-172645 and JP 2002-353141 under 35 U.S.C. 119.
 Return prepaid postcard.

SEND ALL CORRESPONDENCE TO:

MURAMATSU & ASSOCIATES
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Suite 310
Irvine, CA 92618
Tel: 949-753-1127


Signature

Yasuo Muramatsu
Printed Name

38,684
Registration Number